

*IN THE UNITED STATES PATENT AND TRADEMARK OFFICE*

In re PATENT APPLICATION of :  
Ki-Hwan PARK et al. :  
Serial No. [NEW] :  
Filed: October 30, 2003 :  
  
METHOD OF AND APPARATUS FOR CLEANING SEMICONDUCTOR  
WAFERS

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**PRELIMINARY AMENDMENT**

U.S. Patent and Trademark Office  
2011 South Clark Place  
**Customer Window, Mail Stop Patent Application**  
Crystal Plaza Two, Lobby, Room 1B03  
Arlington, VA 22202

Sir:

Prior to the examination of the above-identified application, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins of page 2 of this paper.

**Remarks** begin on page 6 of this paper.